



INFORMATION DISCLOSURE STATEMENT BY APPLICANTS	ATTY. DOCKET NO. 2369/31	SERIAL NO. 09/802,975
	APPLICANTS Haroon AHMED, et al.	
	FILING DATE March 12, 2001	GROUP 2881

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS/ SUBCLASS	FILING DATE
<i>9/12</i>	5,478,698	12/26/95	Rostoker, et al.		
<i>9/12</i>	5,654,548	08/05/97	Fink, et al.		
<i>9/12</i>	5,955,850	09/21/99	Yamaguchi, et al.		
<i>9/12</i>	6,019,913	02/01/00	Dinh, et al.		

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION	
					YES	NO
<i>9/12</i>	0 366 851	09/05/90	Europe		Yes	
<i>9/12</i>	0 633 593 A1	11/01/95	Europe		Yes	
<i>9/12</i>	WO 96/10836	11/4/96	WIPO		Yes	
<i>9/12</i>	WO 97/18577	22/5/97	WIPO		Yes	
<i>9/12</i>	0 905 737 A1	31/03/99	Europe		Yes	

OTHER DOCUMENTS

EXAMINER INITIAL	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
<i>9/12</i>	"Hybrid atomic force/scanning tunneling lithography", K. Wilder, et al., Journal of Vacuum Science and Technology, vol. B15, pp. 1811-1817 (1997)
<i>9/12</i>	"Experimental evaluation of a 20 x 20 mm footprint microcolumn", E. Kratschmer, et al., Journal of Vacuum Science and Technology, vol. B14, pp 3792-3796 (1996)
EXAMINER <i>James J. Lyfman</i>	DATE CONSIDERED <i>8/10/03</i>
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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<i>JP</i>	"Nanoscale Field Emission Structures for Ultra-Low Voltage Operation At Atmospheric Pressure", A.A. G. Driskill-Smith, et al. Applied Physics Letters, vol. 71, pp. 3159-3161 (1997)
<i>JP</i>	"A Nanoscale Field-Emission Tube" by A.A. G. Driskill-Smith, et al., Applied Physics Letters, vol. 75, pp. 2845-2847 (1999)
<i>JP</i>	"Fabrication of Integrated Micromachined Electron Guns", W. Hofmann, et al., Journal of Vacuum Science & Technology: Part B, US, American Institute of Physics, New York, Vol. 13, NR, 6, Page(s) 2701-2704.
<i>JP</i>	"Scanning Electron Microscope Using Atomically Fine Field Emission Tip", IBM Technical Disclosure Bulletin, US IBM Corp., New York, Vol 37, NR. 10, pp 463-465
<i>JP</i>	"A Novel Scanning Tunneling Microscope Controlled Field Emission Microlens Electron Source", Journal of Vacuum Science and Technology: Part B, US, American Institute of Physics. New York, Vol. 7, NR. 6, Page(s) 1851-1854
<i>JP</i>	"Integrated Polysilicon and DRIE Bulk Silicon Micromachining for an Electrostatic Torsional Actuator", by J-L. A. Yeh, et al., Journal of Micromechanical Systems, vol. 8, pp 456-465 (1999)
EXAMINER <i>James J. Laybourne</i>	DATE CONSIDERED <i>6/10/03</i>
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